

Attorney's Docket No.: 42P17282

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Patent Application of:

Hok-Kim Choi, et al.

Application No: 10/750,199

Filing Date: December 30, 2003

For: A METHOD TO ASSAY
SACRIFICIAL LIGHT ABOsorbing
MATERIALS AND SPIN ON GLASS
MATERIALS FOR CHEMICAL
ORIGIN OF DEFECTIVITY

Examiner: Daniel S. Larkin

Art Unit: 2856

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION/AMENDMENT

Sir:

In response to the Office Action mailed November 30, 2005, Applicants respectfully request the Examiner to enter the following amendments and consider the following remarks:

FIRST CLASS CERTIFICATE OF MAILING

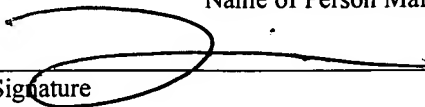
I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on January 31, 2006

Date of Deposit

Trina Chau

Name of Person Mailing Correspondence


Signature

January 31, 2006

Date